

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Shigeharu Monoe
Serial No. : New Application
Filed : June 26, 2003
Title : METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE

Art Unit : Unknown
Examiner : Unknown

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Copies of the references listed on the attached form PTO-1449 are enclosed.

This statement is being filed with the application. Please apply any charges or credits to
Deposit Account No. 06-1050.

Respectfully submitted,

Date: June 26, 2003



John F. Hayden
Reg. No. 37,640

Fish & Richardson P.C.
1425 K Street, N.W.
11th Floor
Washington, DC 20005-3500
Telephone: (202) 783-5070
Facsimile: (202) 783-2331

Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 12732-158001	Application No. New Application
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Shigeharu Monoe	
		Filing Date June 26, 2003	Group Art Unit

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	6,235,558	05/22/2001	Oda et al.			03/31/2000
	AB	US 2001/0030322 A1	10/18/2001	Yamazaki et al.			02/02/2001
	AC	US 2001/0035526 A1	11/01/2001	Yamazaki et al.			04/24/2001
	AD	US 2001/0055841 A1	12/27/2001	Yamazaki et al.			04/12/2001
	AE	US 2002/0158288 A1	10/31/2002	Yamazaki et al.			02/21/2002
	AF						
	AG						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
✓	AH	07-106346	04/21/1995	Japan			ABS	
✓	AI	08-45906	02/16/1996	Japan			ABS	
✓	AJ	10-10752	01/16/1998	Japan			ABS	
✓	AK	2000-294787	10/20/2000	Japan			ABS	
✓	AL	EP 1 128 430 A2	08/29/2001	Europe				
✓	AM	2001-313397	11/09/2001	Japan			ABS	
✓	AN	2002-14337	01/18/2002	Japan			ABS	

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	AO	M. Nagase et al.; "Study of sub-30nm gate Etching Technology"; <i>2001 Dry Process International Symposium</i> ; pp. 17-22; 2001
	AP	
	AQ	
	AR	

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	